

**Notice of References Cited**

Application/Control No.

10/544,787

Applicant(s)/Patent Under  
Reexamination  
ROCA I CABARROCAS ET AL.

Examiner

DANIEL WHALEN

Art Unit

2829

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**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-5,403,756 A	04-1995	Yoshinouchi et al.	438/162
*	B	US-6,078,059 A	06-2000	Nakata, Yukihiro	257/57
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	M	US-			

**FOREIGN PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
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**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Roca et al., "Stable microcrystalline silicon thin-film transistors produced by the layer-by-layer technique", Journal of Applied Physics, 1999 American Institute of Physics, pages 7079-7082
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\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.